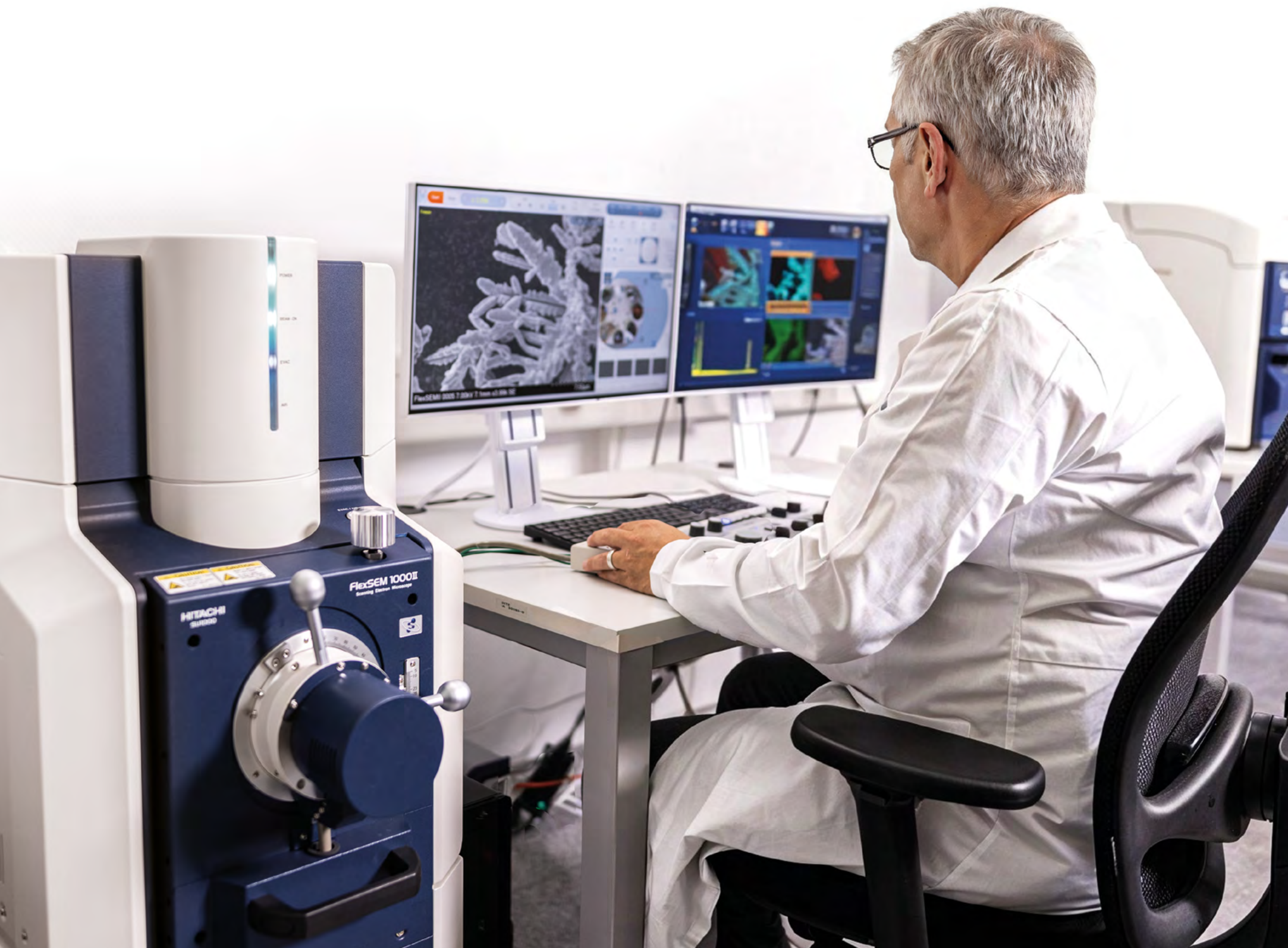


# Table Top/ Compact SEM

**HITACHI**



TM4000III



FLEXSEMII



# TM4000III

SEM imaging and elemental analysis made easy



Thermionic  
Tungsten  
Emitters



## Beyond Optical Stereo Microscopy

Designed as a compact but powerful microscope to provide topographical and compositional information quickly and easily for any user. Variable vacuum technology ensures uncoated, insulating materials can be imaged without difficulty. Optional EDS provides fast chemical composition and elemental distribution information. Sample navigation is made easy with the motorized stage and integrated optical navigation camera.

### Product Features

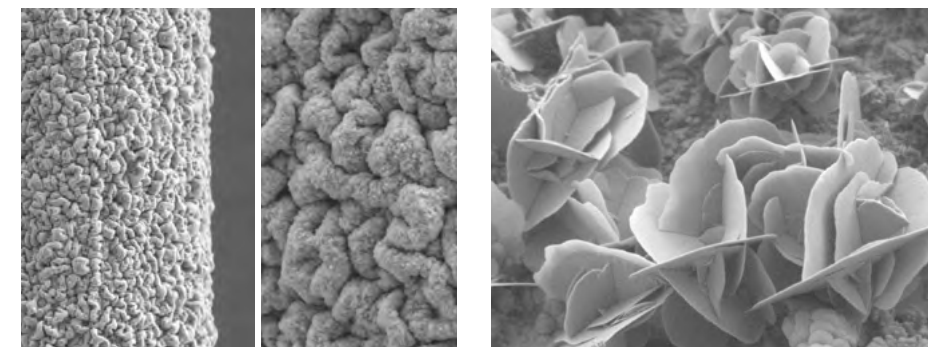
- 4-segment backscattered electron detector offering both compositional and topographical information.
- Variable pressure enables handling of conductive and non-conductive specimens.
- Acceleration voltage range. 20kV with adjustable probe current.
- Probe current reading Intelligent Filament Technology (IFT) ensures optimum filament performance.
- Navicam for fast sample navigation.

### Optional Accessories

- EDS with sensor sizes up to 65mm<sup>2</sup> coupled with high probe current provides fast elemental analysis and mapping.
- Fully automated EDS particle and feature analysis.
- Automatic multi-field image capture ("Multi-zigzag").
- Advanced automation with EM Flow Creator. (See pages 48-49)
- Hitachi Map 3DPackages for additional functions such as 3D reconstruction, ISO-standard roughness measurement, Particle, fibre and pore analysis, image processing, colour segmentation, etc.
- Brightfield STEM detector for transmitted electron imaging.

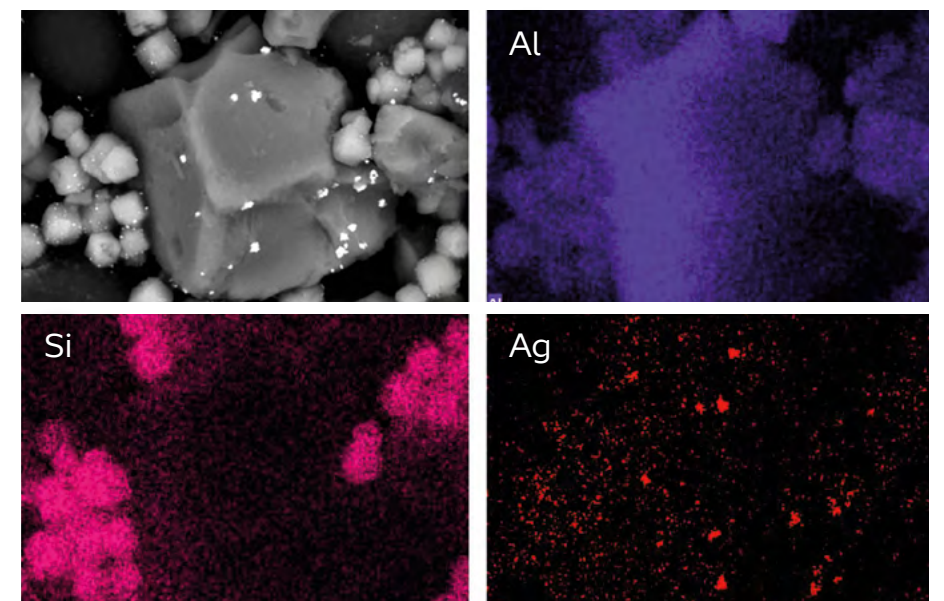


The specimen stage withdraws completely from the chamber for easy sample changes



Corroded copper wire  
10kV, SE signal

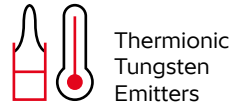
Copper sulphide crystals  
5kV, SE signal



Cosmetic powder, EDX analysis. 15kV

# FlexSEMIII

Full SEM functionality in a compact design



Thermionic  
Tungsten  
Emitters



## Compact high performance SEM

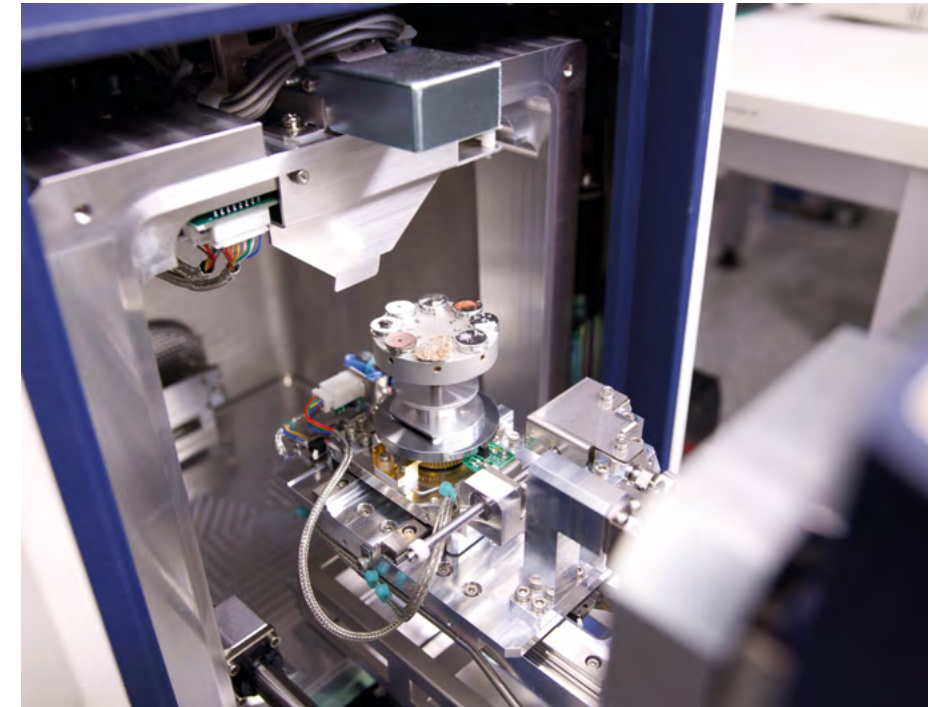
The FlexSEMII provides space efficient, cost effective full-size SEM performance in a table-top/compact format. When imaging tasks go beyond the capabilities of conventional table-top SEMs the FlexSEMII is the ideal solution.

### Product Features

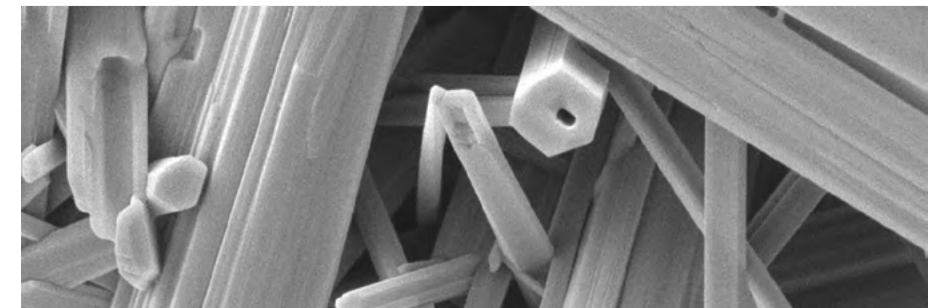
- 4nm @ 20kV high-resolution electron optics with accelerating voltage range of 300eV- 20keV.
- High vacuum and variable low vacuum (6-100Pa) for imaging of conductive and non-conductive specimens.
- 5-axis sample stage for samples up to 80mm (153mm option) diameter and 40mm height.
- Secondary electron and 5 segment backscatter electron detector as standard, UVD low vacuum SE detector optional (including cathodoluminescence imaging).

### Optional Accessories

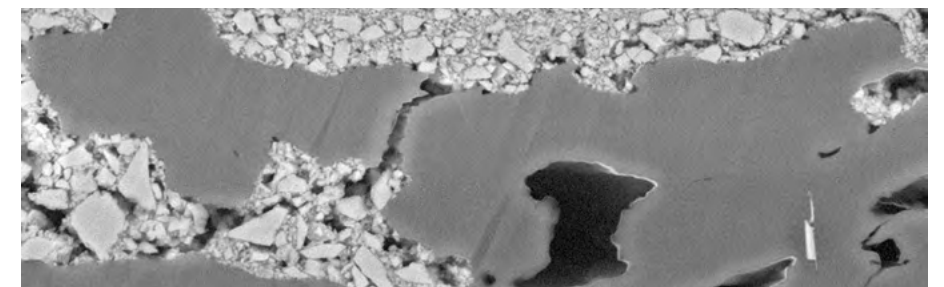
- EDS with sensor sizes up to 65mm<sup>2</sup> coupled with high probe current provides fast elemental analysis and mapping.
- Fully automated EDS particle and feature analysis.
- Advanced automation with EM Flow Creator. (See pages 48-49)
- Hitachi Map 3DPackages for additional functions such as 3D reconstruction, roughness measurement, particle, fibre and pore analysis, image processing, and colour segmentation.
- Brightfield STEM detector for transmitted electron imaging.



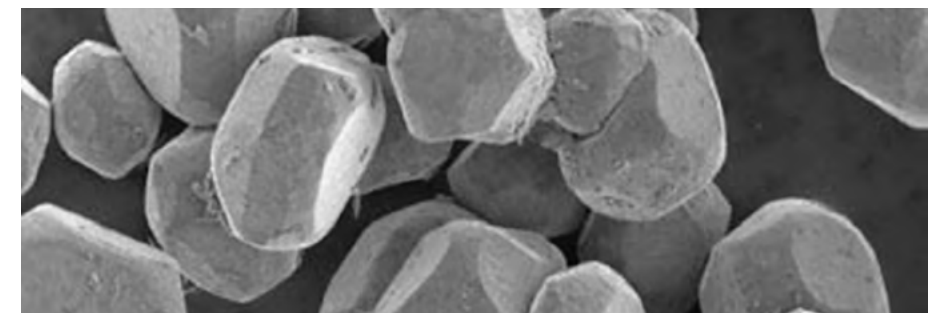
*Eucentric 5-axis specimen stage*



*Pharmaceuticals, 4.0kV, magnification 7,500x*



*Paper, 10.0kV, magnification 2,700x*



*Phosphor, 1.5kV, magnification 5,000x*

## Not sure which product aligns with your needs?

Our experts are here to provide guidance and help you make the best choice.

[Speak with an expert >](#)

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